

BEST AVAILABLE COPY

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>	Docket Number (Optional) TWI-15220		Application Number NEW- 10/696,269	
	Applicant(s) Jon Opsal			
	Filing Date HEREWITH		Group Art Unit Unknown- 2877	

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
HP ↑	*AA	3,992,105	11/16/1976	White	356	369	03/10/1975
	*AB	4,053,232	10/11/1977	Dill et al.	356	369	04/28/1975
	*AC	4,158,506	06/19/1979	Collett	356	365	11/15/1977
	*AD	4,286,843	09/01/1981	Reyblatt	359	489	05/14/1979
	*AE	4,999,014	03/12/1991	Gold et al.	356	382	05/04/1989
	*AF	5,042,951	08/27/1991	Gold et al.	356	369	09/19/1989
	*AG	5,166,752	11/24/1992	Spanier et al.	356	369	01/11/1990
	*AH	5,181,080	01/19/1993	Fanton et al.	356	381	12/23/1991
	*AI	5,329,357	07/12/1994	Bernoux et al.	356	369	04/21/1993
	*AJ	5,412,473	05/02/1995	Rosencwaig et al.	356	351	07/16/1993
	*AK	5,596,411	01/21/1997	Fanton et al.	356	369	03/18/1996
	*AL	5,608,526	03/04/1997	Piwonka-Corle et al.	356	369	01/19/1995
	*AM	5,889,593	03/30/1999	Bareket	356	445	02/26/1997
	*AN	6,278,519	08/21/2001	Rosencwaig et al.	356	369	01/29/1998
	HP	*AO	US 2002/0038196	03/28/2002	Johnson et al.	702	179

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
HP	*AP	6-117935	04/28/1994	Japan	G01J	4/04	

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

HP	*AQ	J.M. Leng et al., "Characterization of titanium nitride (TiN) films on various substrates using spectrophotometry, beam profile reflectometry, beam profile ellipsometry and spectroscopic beam profile ellipsometry," <i>Thin Solid Films</i> , Vol. 313-314, 1998, pp. 308-313.

Examiner <i>Pranish</i>	Date Considered <i>4/30/04</i>
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	